

# Signatone WL - 250 200 mm Semi-Automatic Probe System

## For reliable and accurate RF-mmW-THz, DC/CV, and High Power Test Measurements

### ❖ FEATURES / BENEFITS

#### Designed for a Variety of On-Wafer Analytical and Semi-Production Applications

- RF applications up to 110GHz 2 & 4 port setup
- mmW 110GHz -1.5THz 2-Port
- DC, CV/IV, pulsed -IV applications
- High Power Application up to 12KV /600A
- IC Design / test verification Ambient, +300°C
- -60 °C to +300 °C when use with Local Enclosure EMI / RFI / Light-Tight Shielding (optional).

#### Product Versatility

- Designed for full or partial wafer probing
- Roll-Out stage for ease of wafer loading
- Active Vibration Isolation table (optional)
- Ambient, Hot (+300°C) and Hot /Cold (-60 °C to +300 °C) configurations

#### Options and Configurations

- Standard Platen Supports up to 4x RF + 4x DC, 2-mmW+2RF or DC, or 10x DC MicroPositioner and/or 4.5" wide probe card
- Available in multiple configurations including a variety of chuck options, DC/RF/High Power positioners, Computer Aided Probes, microscopes, camera's, Dark Box's, lasers for various applications



### ❖ ROLL - OUT STAGE

- Roll-Out Stage designed for easy Loading and Unloading of Wafer Samples and single ICs
- Excellent for use with probe cards and multi probe/complex setups
- Allows easy access to AUX -chucks
- Lock and Un-Lock position indicator
- Presentation 190mm / 95%
- Easy access to vacuum-zone selector knob
- Simplifies use with Local Enclosure option

## ❖ SPECIFICATIONS

### Chuck XY Stage (Programmable)

Travel range	205 mm x 205 mm (8.07 x 8.07 in)
Resolution	0.5 µm
Accuracy	± 2.0 µm*
XY stage drive	Closed-loop high precision servo motor PID control
Speed	Variable Speed XY chuck stage control
Max. movement speed	120 mm / sec.

### Chuck Z Stage (Programmable)

Travel range	12.5 mm (0.5 in)
Resolution	0.25 µm
Accuracy	± 2.0 µm
Repeatability	± 1.0 µm
Z stage drive	Closed-loop micro stepper motor
Speed	Variable Mode and Speed selection
Max. movement speed	15 mm / sec.

### Chuck Theta Stage (Programmable)

Travel range	± 7.5° (15°)
Resolution	0.000035°
Accuracy	< 1.0 µm (measured at the edge of the 200 mm chuck)
Repeatability	< 1.5 µm
Theta stage drive	High resolution stepper motor, rotary encoder feedback system

### Roll Out / Loading Stage

Travel range	195mm
Presentation	190mm
Return repeatability	< 1µm

### Motorized Microscope Stage (linear)

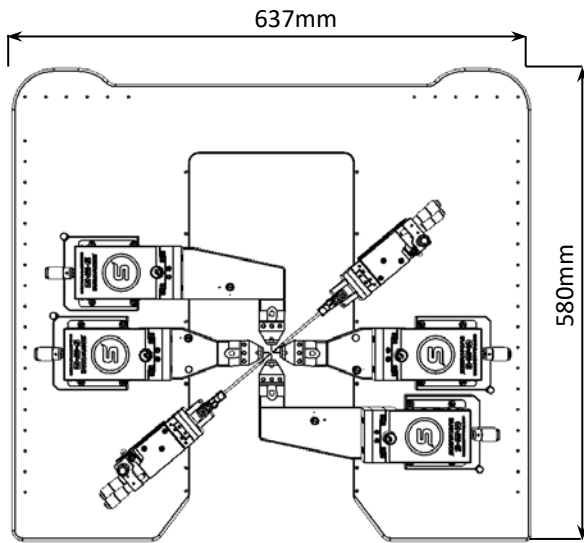
Movement range	50mm X 50mm (2"x2")
Resolution	0.02µm (20 Nano meters)
Scope lift	101 mm (4") Vertical Pneumatic (Motorized- optional)
Scope lift motorized (optional)	50mm motorized + 50 mm pneumatic / combination = 101mm (4")

\*All data relevant for use with Precision package

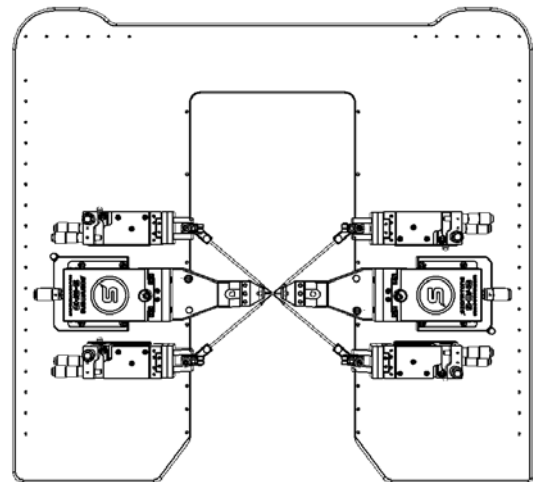
## ❖ PROBE PLATEN

### Specifications

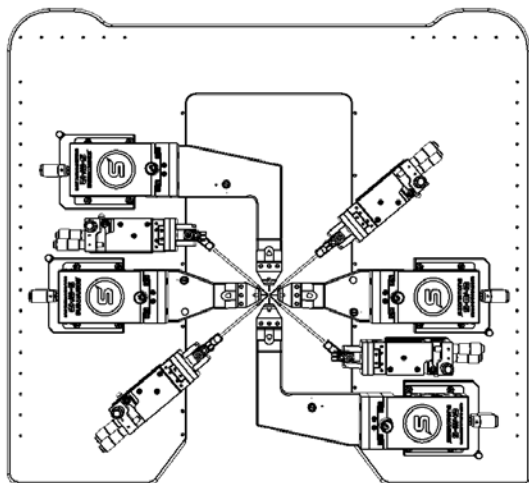
Material	Nickel Plated Steel (Al optional)
Dimension	L = 580mm x W = 637mm x H = 12.7mm (See drawing)
Chuck to Thermal Shield Separation	Min. 2 mm (Variable Separation with Fine Platen Adjust)
Max. No of Micro Positioners	4x RF + 2x DC or 2x RF + 4 x DC or 4x RF + 4x DC or 10x DC
Quick Platen Lift Control (CVL)	Continuous Variable Lift (0 to 3.175 mm)
Contact Repeatability	< 1 $\mu$ m (0.04 mils) by Manual Control
RF MicroPositioner mounting	Magnetic or Bolt Down
DC MicroPositioner mounting	Magnetic or Vacuum
Thermal Isolation (Optional)	Platen Temp = +15 $^{\circ}$ C to +40 $^{\circ}$ C /chuck @ -60 $^{\circ}$ C to +300 $^{\circ}$ C



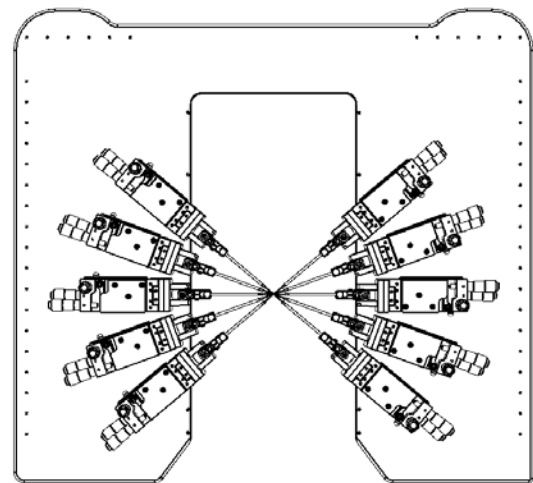
Sample 1: Probe Configured with 4 RF + 2 DC Probes



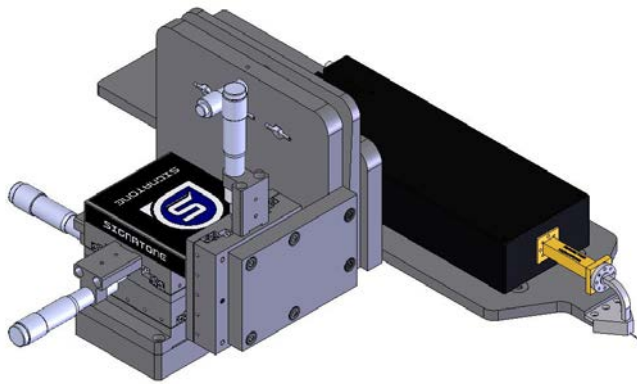
Sample 2: Probe Configured with 2 RF + 4 DC Probes



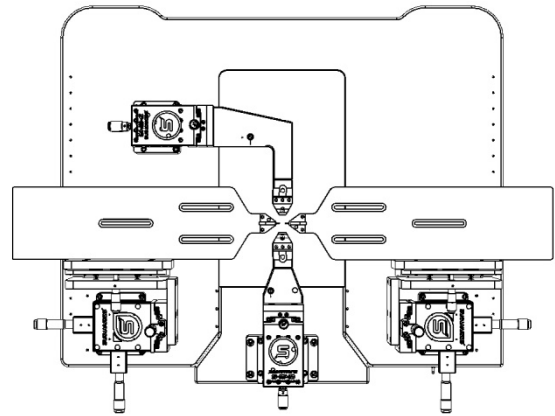
Sample 3: Probe Configured with 4RF + 4 DC Probes



Sample 4: Probe Configured with 10 DC Probes



Large Area Positioner w/ Frequency Extender



Sample 5: 2x mmW + 2 RF probes

### ❖ ONE PLATEN x 4 BENEFITS

#### Signatone Multi Benefit Ergonomically Correct Platen Adjust and Features:

- “Quick Lift” with CVL for easy probe to pad separation and alignment
- “Fine Adjust” for Probe card and variable Chucks and DUT thickness setup
- “Position Lock” allows for secure “lock” of user defined platen height setup
- “Thermal Isolation” maintains a safe temperature of probes and platen surface while chuck is at extreme temperatures (optional)



Platen “Quick Lift”



Platen “Fine Adjust” and  
“Position Lock”

## ❖ DC PROBE –SELECTION GUIDE

	Coax Probe (C)	Triax Probe (T)	Kelvin Probe (K)
Max voltage	500 V	500 V	500 V
Temperature range	-60 °C to 300 °C	-60 °C to 300 °C	-60 °C to 300 °C
Leakage current	< 50fA	< 20fA	< 20fA
Connectivity	BNC	Standard Triax	SSMC
Connectivity type	Single Coaxial	Single low noise Triaxial	Force/Sense Coax
Characteristics impedance	50 Ohms	50 Ohms	50 Ohms
Residual capacitance	< 80fF	< 80fF	< 80fF
Probe holder material	Brass	Brass	Brass
Probe tips material	Tungsten	Tungsten	Tungsten
Probe tips sizes	0.5 µm – 25 µm	0.5 µm – 25 µm	0.5 µm – 25 µm
Minimum pad size	25 µm x 25 µm	25 µm x 25 µm	25 µm x 25 µm



Coax Probe



Triax Probe



Coax Kelvin Probe

\*All leakage tests conducted in an enclosed environment with Keithley 4200, or equivalent, in sampling mode with 10 PLC, auto-ranging. 0.25s interval

## ❖ High Voltage/High Current PROBE –SELECTION

Model	High Voltage Probes			High Current Probe
	HVP-CX-3	HVP-TX-3	HVP-CX-10	HCP 100
Max Voltage	3 kV	3 kV	10 kV	500 V
Max Current	1 A DC/30 A Pulsed	120 mA DC	20 mA DC	10 A DC/100 A Pulsed
Temperature Range	-60 °C to 300 °C	-60 °C to 300 °C	-60 °C to 300 °C	-60 °C to 300 °C
Leakage Current	< 200 pA @ 3 kV, < 5 pA @ 10 V	< 1 pA @ 3 kV, < 100 fA @ 10 V	< 100 pA @ 10 kV	N/A
Connector Type	SHV	HV Triax	UHV Coax	HV Banana
Replaceable Tip	Yes	Yes	Yes	Yes
Probe Material	W	W	W	BeCu or W



HVP-CX-3



HVP-TX-3



HVP-CX-10



HCP-100

## ❖ SYSTEM CONTROLS

The S1080 thermal chuck controller features touch screen commands, triple safety circuits, and 0.1° resolution. **ProbeMaster** software features thermal control from the probe station.

Hardware accessories including keyboards and mouse can be easily integrated into the table's instrumentation rack providing greater ease of use, ergonomics, and minimizing the overall system dimensions. System and thermal controllers may also be integrated.

Industry proven precision Joy Stick/ thumbwheel combination, intuitive selector panel for DUT, Microscope, and 1-4 Computer Aided Probes (CAP). LED indicator for active device, Multi-speed thumbwheels offer sub-micron positioning.



## ❖ SYSTEM SOFTWARE

Signatone's powerful navigation software **ProbeMaster** drives all Signatone semiautomatic probing systems. **ProbeMaster** simplifies navigation to a test site by using arrow keys, wafer graph or *point and shoot* on the live image. The optional vision control module includes *auto align*, *auto start*, *probe exact*, and *sure touch* features. Supports many popular interface protocols \* [see supported software platforms](#)

**Go to HOME Location**

**SW ABORT**

**WAFER MAP**  
Programmed Points, Reports X-Y Position - Row/Column. Click and Move to Die Location, Color Map..

**Device Selector**  
Indicates Wafer, Scope, Probe 1-4

**Wafer "Load / Un-Load"**

**Program Points**  
**Program Sub-Sites**

**On-Screen Live Image**  
Allows Image Capture and "Point -Shoot" navigation of Selected Device

**Thermal Chuck Control Software**  
0.1° resolution / RS-232 interface

**Joystick Status**

**Move or Step Direction Keys**

## ❖ NON-THERMAL CHUCKS

### Standard Wafer Chuck

Connectivity	Coax BNC (m)
Diameter	203 mm
Material	Nickel Plated Brass (gold optional)
Chuck surface	Zone selector knob with Peppered vacuum patterns
Vacuum hole pattern sections(diameter)	22mm, 50mm, 91mm, 135mm, 168mm
Vacuum actuation	Selector Knob allows individual activation of vacuum zones
Supported DUT sizes	25mm, 75mm, 100mm, 150mm, 200mm
Surface planarity	±6.5μ
Rigidity	<3μ / 10N at edge of the chuck

### Electrical Specification (Coax)

Operation voltage	Designed for operation at -200V to + 200VDC
Maximum voltage between chuck top and GND	500 V DC
Isolation	> 150 GΩ

### Wafer Chuck (Triaxial)

Connectivity	Triax (m)
Diameter	203 mm
Material	Gold Plated Brass
Chuck surface	Independent Vacuum zones with vacuum rings
Vacuum hole pattern sections(diameter)	0mm, 65mm, 112mm, 162mm
Vacuum actuation	Multi-Zone Adjustable Control
Supported DUT sizes	3mm, 75mm, 125mm, 200mm
Surface planarity	± 5 μm
Rigidity	<3μ / 10N near at edge of the chuck

### Electrical Specification (Triax)

Chuck isolation	Measured @ 10V DC
Force to guard	> 2 TΩ
Guard to shield	> 7 TΩ
Force to shield	> 15 TΩ

### Auxiliary Chuck

Quantity	2 AUX chucks
Position	Independently isolated (located on back left and right )
Substrate Size (L x W)	Max 25mm x 25mm (1"x 1")
Material	Ceramic, Ultem, or NI plated brass
Surface Planarity	≤± 5 μm
Vacuum Control	Controlled independently, separate from wafer chucks

## ❖ SIGNATONE THERMAL CHUCKS

### Typical Specifications of *Signatone* Thermal Technology

	200mm Standard Hot	200mm Hot/ Triax	200mm Hot/ 3kV Triax
Temperature Range	+25 °C to +300 °C	+25 °C to +200 °C	+25 °C to +200 °C
Connectivity	Coax (m)	Triax (m)	SHV Triax (m)
Temperature control method	Liquid Cooled / Resistance heater	Liquid Cooled / Resistance heater	Liquid Cooled / Resistance heater
Coolant	Water	Water	Water
Smallest temperature selection step	0.1 °C	0.1 °C	0.1 °C
Chuck temperature display resolution	0.01 °C	0.01 °C	0.01 °C
External touchscreen display operation	Yes	Yes	Yes
Temperature stability	±0.1 °C	±0.1 °C	±0.1 °C
Temperature accuracy	±0.5 °C	±0.5 °C	±0.5 °C
Control method	Low noise DC/PID	Low noise DC/PID	Low noise DC/PID
Interfaces	RS232C	RS232C	RS232C
Optional Interfaces	GP-IB	GP-IB	GP-IB
Chuck surface plating	Nickel	Gold	Gold
Temperature sensor	RTD	RTD	RTD
Temperature uniformity	±0.5 °C at ≤ 200 °C ±1.5 °C at > 200 °C	±0.5 °C at ≤ 100 °C ±2.5 °C at 200 °C	±0.5 °C at ≤ 100 °C ±3.5 °C at 200 °C
Surface flatness	< ±10 μm	< ±8 μm	< ±15μ
Electrical isolation - Coax BNC (m) / SHV Triax	150nA	> 5TΩ	> 5TΩ
Heating Rates	25°C to 300°C < 12 min	25°C to 200°C < 9 min	25°C to 200°C < 28 min
Cooling Rates	300°C to 25°C < 9min	200°C to 25°C < 8min	200°C to 25°C < 8min
Leakage @ 10 V Kelvin Triax	N/A	<25fA	<400fA
Residual Capacitance		<200fF	<1pF
Maximum voltage between chuck top and GND	500V	500V	3kV
3 Safety Circuits	Yes	Yes	Yes
Vacuum Pattern	Rings	Pin hole	Pin hole
Vacuum Zone (DUT Size)	50, 100, 150, 200mm	2, 50, 100, 150, 200mm	2, 50, 100, 150, 200mm

### System Controller / Dimensions / Weight / Power Consumption

System Model	W x D x H (mm)	Weight (kg)	Weight (Lbs.)	Power cons. (VA)
S-1080	432 x 483 x 267	20.4	45	2000
TC-II	355 x 711 x 610	50.8	112	1500
2XRC-89HL	559 x 610 x 915	135	297	3700



## ❖ ERS HIGH POWER THERMAL CHUCKS

### Specifications of ERS/ SIGNATONE Technology HV 200mm Chucks

Temperature Range	25 °C to 200 °C	25 °C to 300 °C
Connectivity	Kelvin Triax (M),3kV or 10 kV Coaxial	Kelvin Triax (M),3kV or 10 kV Coaxial
Temperature control method	Cooling air / Resistance heater	Cooling air / Resistance heater
Coolant	Air (user supplied)	Air (user supplied)
Smallest temperature selection step	0.1 °C	0.1 °C
Chuck temperature display resolution	0.01 °C	0.01 °C
External touchscreen display (optional)	Yes	Yes
Temperature stability	±0.08 °C	±0.08 °C
Temperature accuracy	±0.1 °C	±0.1 °C
Control method	Low noise DC/PID	Low noise DC/PID
Interfaces	RS232C	RS232C
Chuck surface plating	Gold plated with pinhole surface	Gold plated with pinhole surface
Temperature sensor	Pt100 1/3DIN 4-line wired	Pt100 1/3DIN 4-line wired
Temperature uniformity	< ±0.5 °C at ≤ 200 °C	< ±0.5 °C at ≤ 300 °C
Surface flatness and base parallelism	< ±10 µm	< ±10 µm
Heating and Cooling Rates*	25 to 200°C <30min 200 to 25°C <30min	25 to 300°C <35min 300 to 25°C <35min
Leakage @ 3000V Kelvin Triax (M)		
25°C	5pA	5pA
200 °C	10pA	10pA
300°C	--	15pA
Leakage @ 10kV Coax UHV/SHV (M)		
25°C	6nA	6nA
200 °C	6nA	6nA
300°C	--	6nA
Maximum voltage between chuck top and GND	10 kV DC	10 kV DC

\*All data are relevant for chucks in ECO mode

### System Controller / Chiller Dimensions and Power / Air Consumption

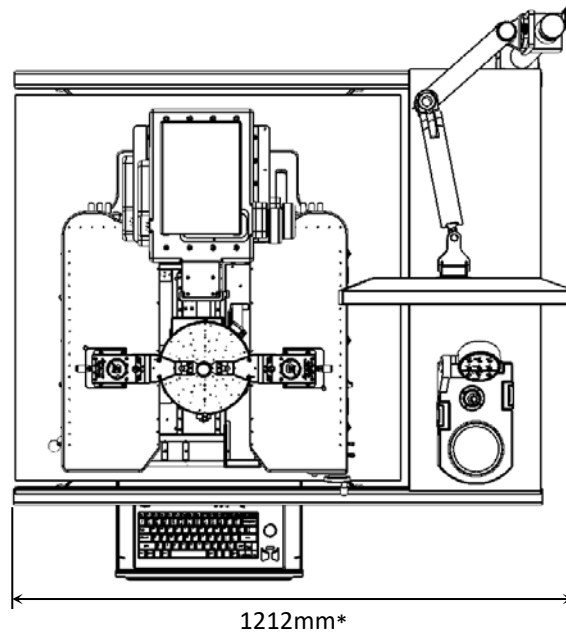
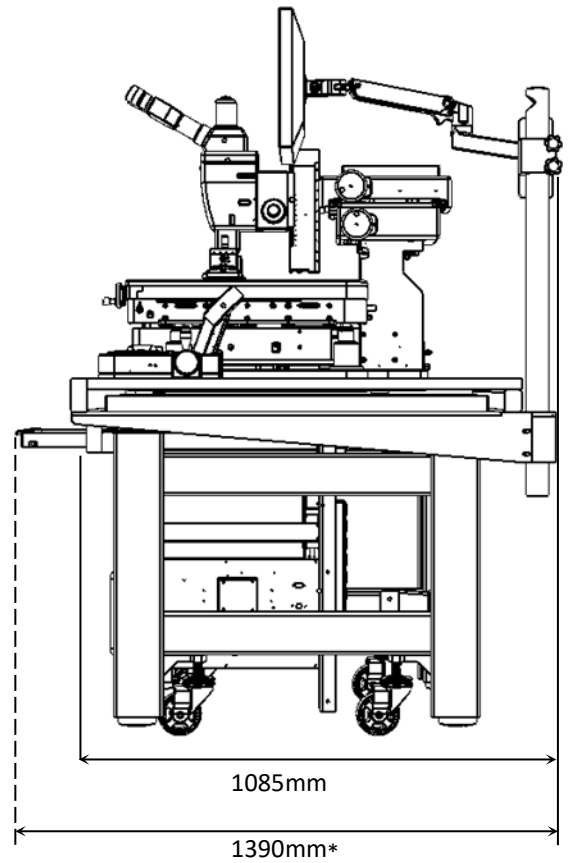
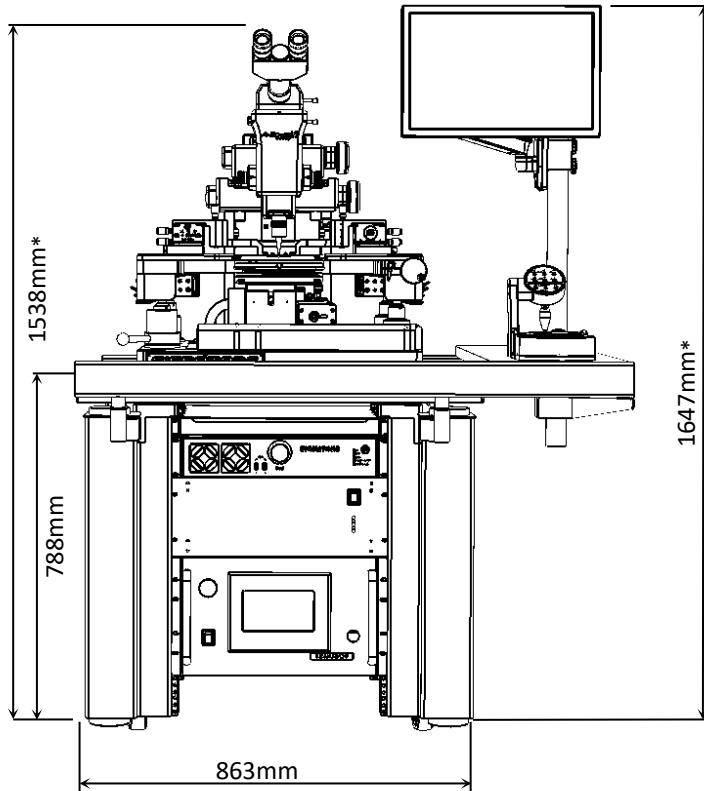
System type	W x D x H (mm)	Weight (kg)	Power cons. (VA)	max. Air flow (l/min)
25 to 200 °C	300 x 360 x 135	12	1300	220
25 to 300 °C	300 x 360 x 135	12	1300	220

**❖ SYSTEM DIMENSIONS INCLUDING TABLE**

**WL-250 / Vibration Isolation Table /Monitor and Keyboard Mount**

Dimensions (L x D x H)	863x 1085 x 1538 mm	(34 x 42.7 x 60.6 In )
Weight	450 kg	(995 lbs.)

*\* Can vary dependent on monitor, keyboard (roll out drawer) position and Microscope selection*

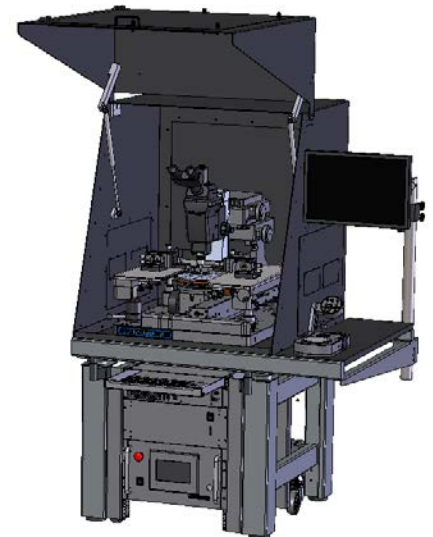
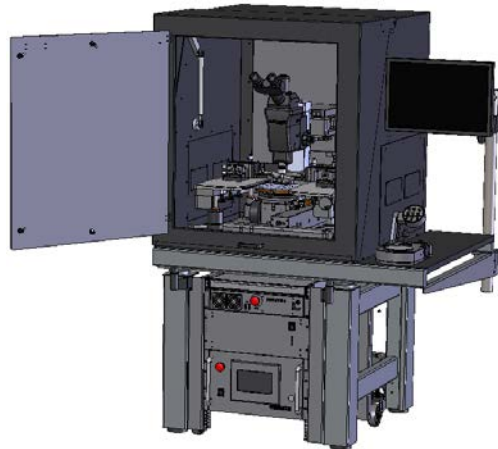
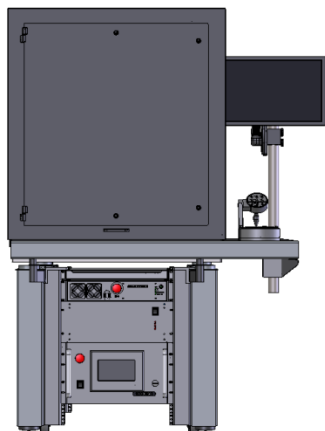
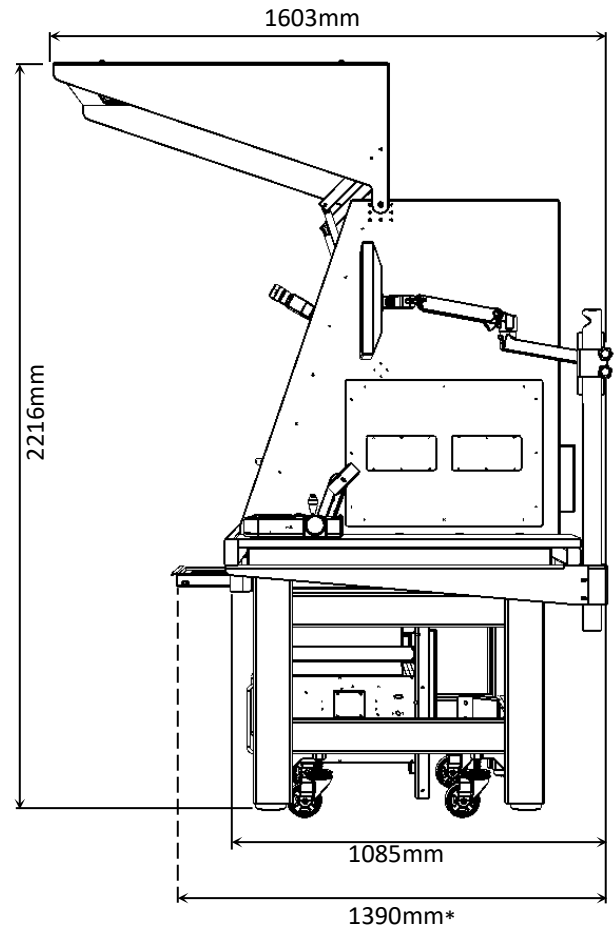
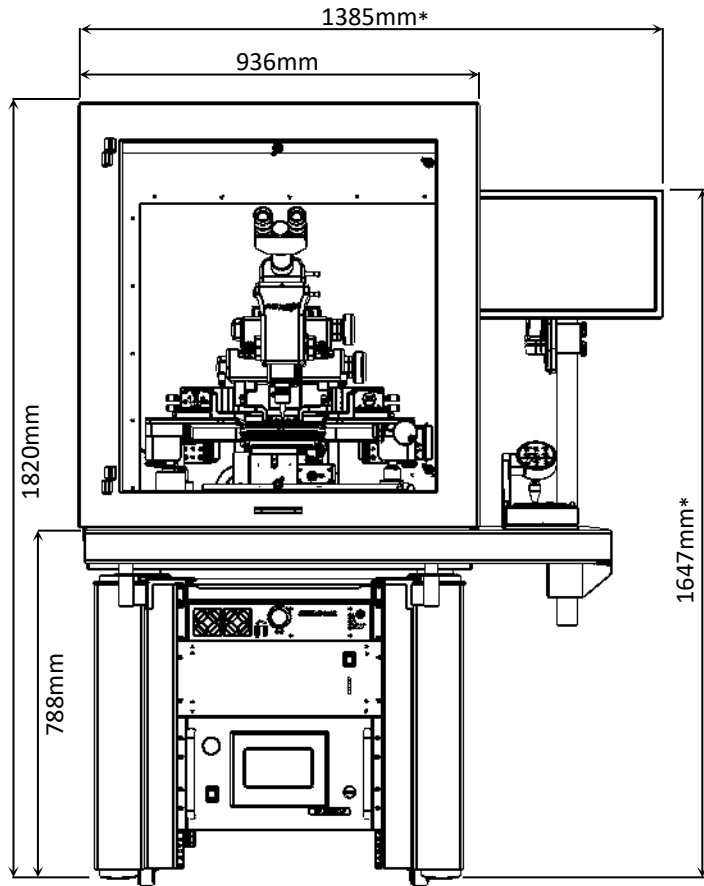


**❖ SYSTEM DIMENSIONS INCLUDING DARK BOX**

**WL-250/PSDB/Vibration Isolation Table/Monitor and Keyboard Mount**

Dimensions (L x D x H)	936 x 1085 x 1820 mm	(36.85 x 42.7 x 71.7 In )
Weight	510 kg	(1125 lbs.)

\* Can vary dependent on monitor, keyboard, and dark-box door position



## ❖ WARRANTY

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- Standard Warranty 12 months \*
- For Extended Warranty and Service Contracts : Contact Signatone Corp. for more information

\* See *Signatone Corporate Terms and Conditions of Sale* for further details.

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